

# Supporting Information

Guo et al. 10.1073/pnas.0907390106

## SI Materials and Methods

**Mechanics Model.** Using the Bernoulli beam theory (1), the governing differential equation for a tapered beam under small deflection is given by

$$B_x \frac{d^2 w}{dx^2} = P(L_p - x) \quad [\text{S1}]$$

where  $w$  is the deflection,  $P$  is the external force exerted at the position  $x = L_p$ ,  $B_x = (1 - x/L)Et_0h^3/12(1 - \nu^2)$  is the local bending stiffness, with  $E$  being the Young's modulus,  $\nu$  the Poisson's ratio,  $t_0$  the width at the beam end, and  $h$  the beam thickness. To examine the bending behavior of a tapered beam with any base angle  $\theta$  (Fig. 3B), one needs to find the equivalence between a tapered beam and a beam of simple geometry. Here, we assume that if the deflections of a tapered beam and a uniform beam are equal at location  $x = L_p$  ( $\delta_{\text{taper}} = \delta_{\text{uni}}$ ), as shown in Fig. 3B, then these two beams are considered "equivalent." The equivalence will lead to an effective bending stiffness  $B_{\text{eff}}$ , which is comprised of the bending stiffness  $B_0$  of a uniform beam with width  $t_0$ , and a nondimensional function  $f(\xi)$ , where  $\xi = L_p/L$  is the location of the fluid-solid junction line. From this Using  $B_{\text{eff}}$ , a nondimensional parameter  $\alpha_{\text{eff}} = \gamma_{\text{eff}}L_p^3/B_{\text{eff}}$ , with  $\gamma_{\text{eff}} = \gamma_0(1 - \xi)$  and  $\gamma_0$  the surface tension, which characterizes the competition between an effective capillary force and the effective bending resistance, can be defined. After inserting the geometric relation  $t_0 = 2L \cot \theta$ , one can readily find that  $\alpha_{\text{eff}}(\xi)$  will reach its maximum value at the critical position  $\xi = \xi_c = 0.77$ , given by:

$$\alpha_{\text{eff}}^{\text{crit}} = 0.816 \frac{\gamma_0 L^2}{E' h^3} \cdot \tan \theta \quad [\text{S2}]$$

where  $E' = E/(1 - \nu^2)$  is the plane strain Young's modulus and  $\theta$  denotes the base angle, shown in Fig. 3B. One concludes that  $\xi_c$  is the location where the folding will occur, as the  $\alpha_{\text{eff}}$  and also the driving force all at their maxima. Eq. 2 shows that the nondimensional parameter  $\alpha_{\text{eff}}^{\text{crit}}$  consists of two dimensionless parts, an intrinsic material parameter

$$\alpha_{\text{int}} = 0.816 \frac{\gamma_0 L^2}{E' h^3} \quad [\text{S3}]$$

that is related to the material properties, including the characteristic dimensions of the structure, and a shape factor  $S(\theta) = \tan \theta$ , which is related to the angle  $\theta$  only.

The mechanics model predicts that, if folding is governed by this nondimensional parameter, then once a combination of the

materials and shape parameters reaches a critical value folding will occur. For any given material, the intrinsic nondimensional materials parameter  $\alpha_{\text{int}}$  given by Eq. 3 is a constant, which can be determined by a single experiment. With this parameter at hand, the folding of foils of different shapes can be predicted solely by the shape factor.

We experimentally measured the intrinsic nondimensional parameter  $\alpha_{\text{int}}$  using a thin Si foil with a uniform beam geometry that is independent of the shape (Fig. S1). The critical length of  $L$  is found to be 0.9 mm for a 1.25- $\mu\text{m}$ -thick Si membrane, giving rise to the intrinsic value of  $\alpha_{\text{int}} = 2.59$ . We note that this nondimensional value should be applicable to thin Si foils of any thickness and length, and can be used to determine the critical conditions for folding of a tapered foil of any angle. The critical nondimensional parameter of any tapered beam of angle  $\theta$  can therefore be expressed by

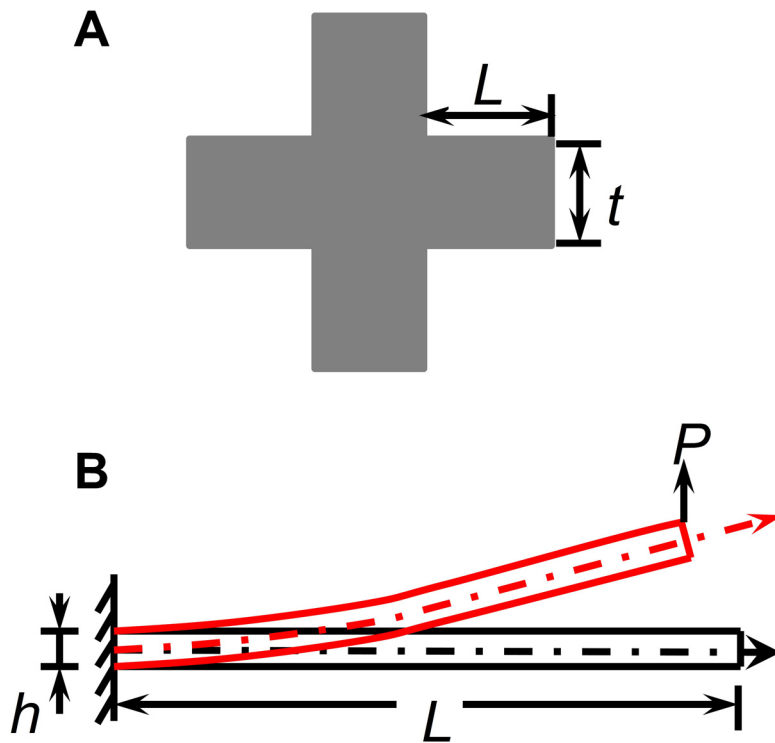
$$\alpha_{\text{eff}}^{\text{crit}}(\theta) = 2.59 \tan \theta \quad [\text{S4}]$$

**Diode J-V Curve Fitting.** Fig. S3 shows the fitting results of a typical 2- $\mu\text{m}$ -thick Si solar cell fabricated in this demonstration. The series resistance is  $\approx 500 \, \Omega$ , which is fairly high and greatly reduces the short circuit current, and the shunt resistance is  $\approx 3 \times 10^5 \, \Omega$ , which is fairly low for a Si solar cell. It seems possible that the polymer shell provides the photoconductive shunt. Also, to enhance the short circuit current density ( $J_{\text{sc}}$ ) an antireflective coating is also needed. Given all these unoptimized issues, it is not surprising to obtain relatively low efficiencies for 2- $\mu\text{m}$ -thick Si devices.

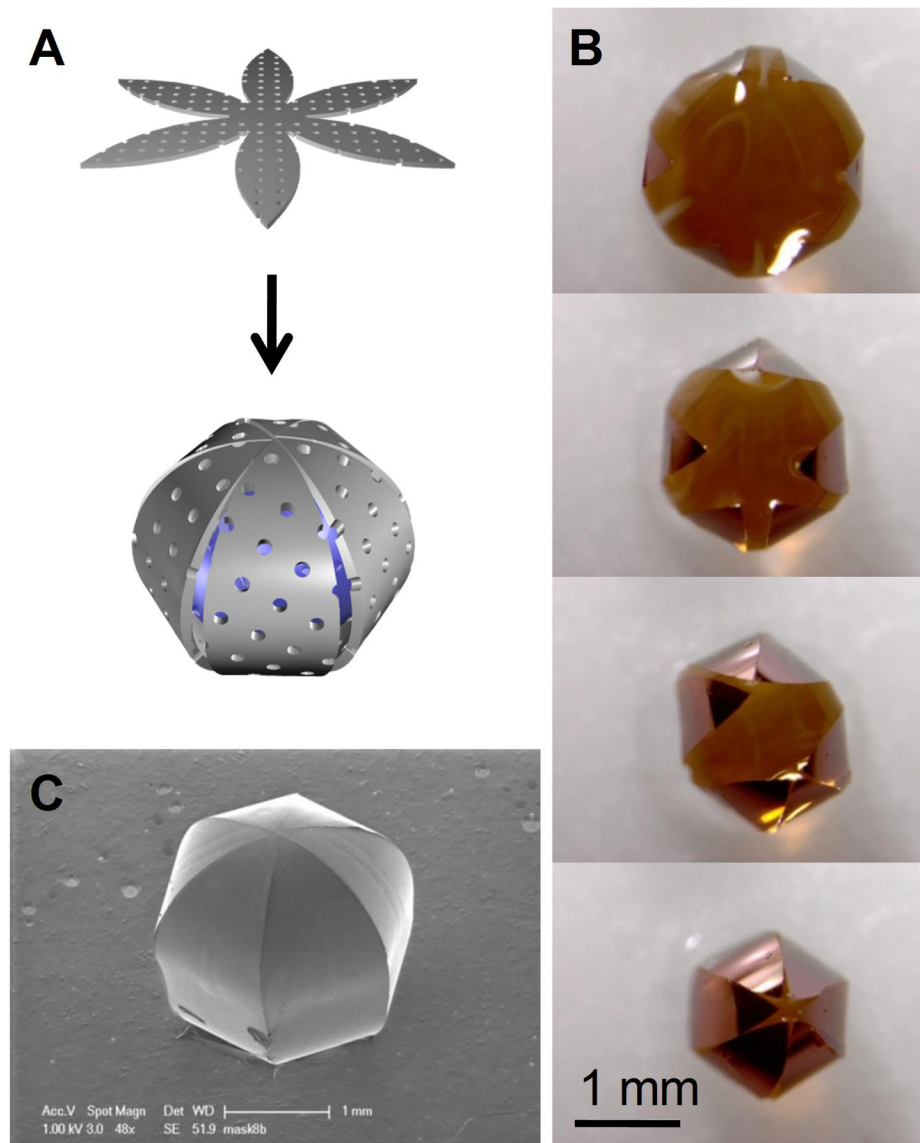
**Direct Ink Writing.** A silver microelectrode was printed on a precleaned glass slide and in contact with the bottom metal contact (Cr/Au) of the spherical cell. Another silver microwire ( $\approx 20 \, \mu\text{m}$ ) was printed directly onto the top metal contact of the spherical cell (Fig. S5B). The printed silver electrodes on Si were made nonrectifying by subjecting them to 3 h of annealing at 200 °C, 20 min of soaking in water, and 3 h of annealing at 250 °C. The ohmic characteristic of this contact is demonstrated by the data given in Fig. S5C.

**Electrical Measurements.** Light and dark J-V measurements of solar cells were carried out at room temperature using a direct current (d.c.) source meter (model 2400; Keithley) operated by LabVIEW5, and a full-spectrum solar simulator (model 91192,  $4 \times 4$  inch source diameter,  $\pm 4^\circ$  collimation; Oriel) equipped with air mass (AM) 0 and AM 1.5 direct filters. The input power of light from the solar simulator was measured with a power meter (model 70260; Newport) and a broadband detector (model 70268; Newport) at the surface where the sample was placed.

1. Gere JM, Timoshenko S (1997) in *Mechanics of Materials* (PWS Pub. Co., Boston), 4th Ed, pp 599–604.

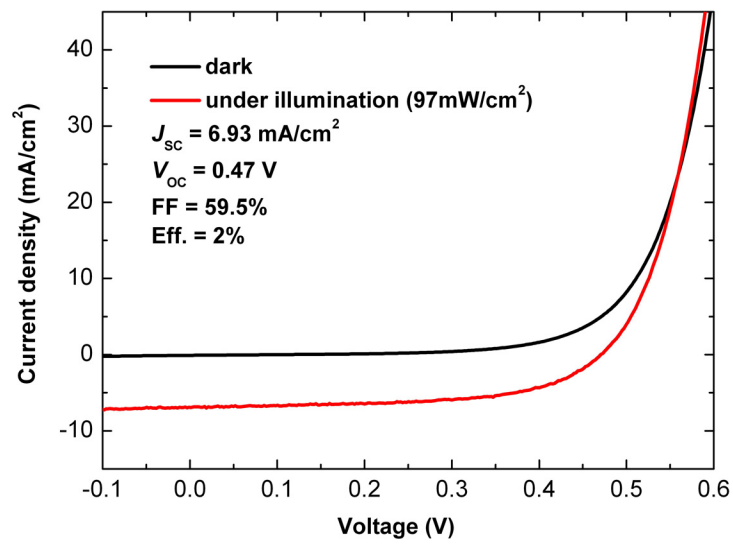


**Fig. S1.** Intrinsic alpha ( $\alpha_{int}$ ) measured from the uniform beam, showing the design of the uniform beam (A) top view and (B) side view.  $L$ ,  $t$ , and  $h$  are the beam length, width, and thickness, respectively.

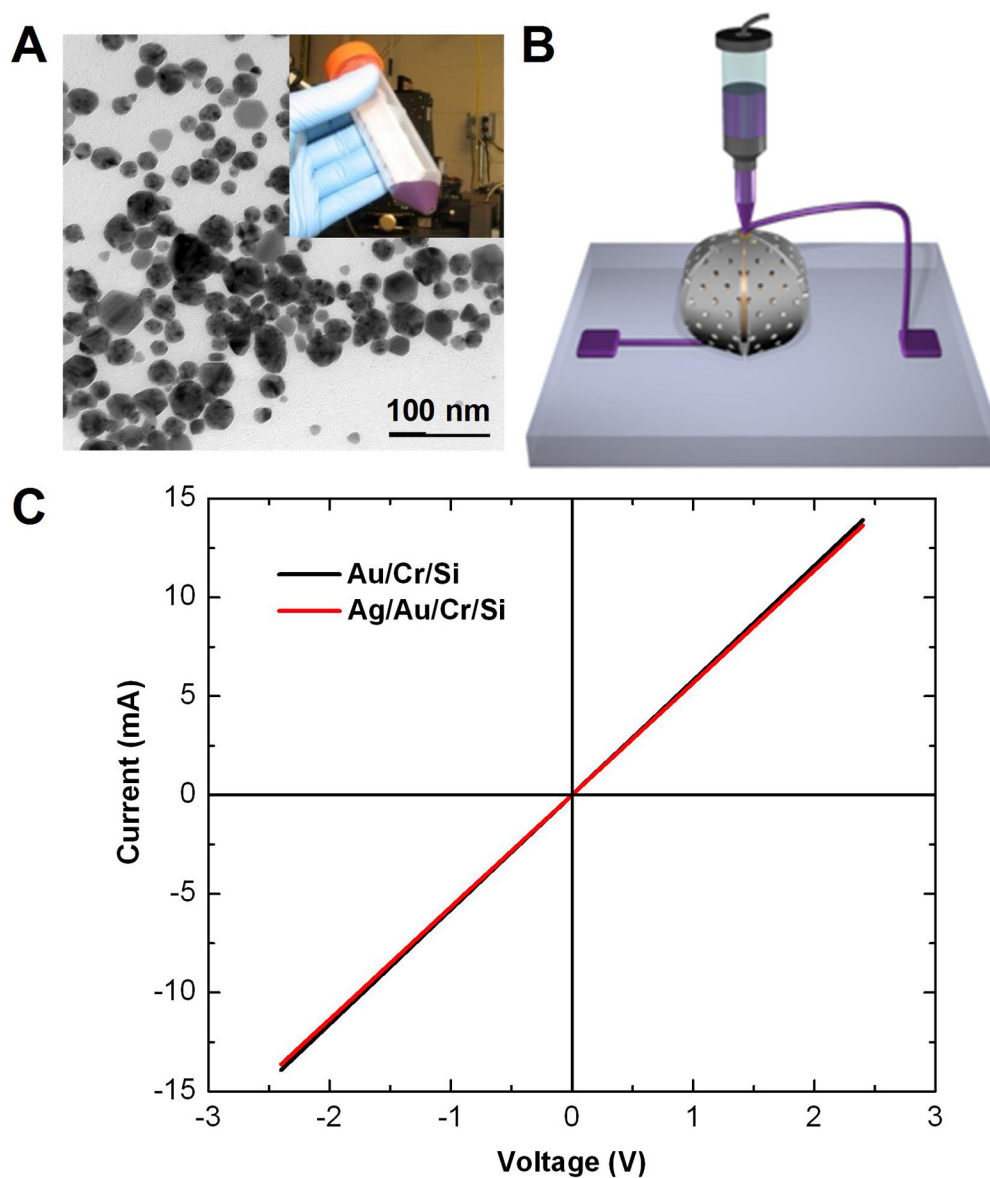


**Fig. S2.** Fabrication of a spherical Si structure. (A) Schematic representation illustrating the folding of the flower shape into a sphere. (B) Wrapping of a water droplet with a flower-shaped Si sheet with thickness of 1.25  $\mu\text{m}$ . (C) SEM micrograph of a spherical-shaped Si structure incorporating an inner glass bead.





**Fig. S4.** Current density-voltage behavior of a 3- $\mu\text{m}$ -thick Si-on-insulator (SOI) solar cell tested on wafer. The whole top surface is coated with an antireflection coating ( $\text{SiO}_2$ , 100 nm).



**Fig. S5.** Direct ink writing (DIW) of silver wires. (A) Transmission electron microscopy (TEM) image of silver nanoparticles designed for direct ink writing (DIW) of silver electrodes on silicon solar cells (*Inset*, optical image of the concentrated silver ink). (B) Schematic representation of printing silver wires as the bottom and top electrodes for a spherical solar cell. (C) Current-voltage behavior of the silver electrodes printed on the Cr/Au (3 nm/50 nm) pads of a test Si wafer after thermal treatment.